

Attorney Docket: 061063-0306825
Client Reference: OSP-15115

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
SHIOTA ET AL.

Confirmation Number: 5650

Application No.: 10/706,266

Group Art Unit: 2811

Filed: November 13, 2003

Examiner: Unassigned

Title: SILICON WAFER AND MANUFACTURING METHOD THEREOF

SUPPLEMENTAL PRELIMINARY AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Further to the Preliminary Amendment filed June 24, 2004, please further amend the above-identified application as follows: